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Erratum

In the article "Queuing Networks with Population Size Constraints" (S. S. Lam, *IBM J. Res. Develop.*, Vol. 21, No. 4, July 1977), page 376 should be amended as follows: $\sigma_r(X_{it}^{+3})$ in Eq. (A2) and $\sigma_r(X_{it}^{+T})$ in Eq. (A3) should both be replaced by $\sigma_r(X_{it}^{+T})$.